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2003-036970

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TITLE:

Method for measuring solid density and primary

particle

size of slurry for chemical mechanical

polishing process

using ultraviolet spectrometer

INVENTOR: CHOI, J S; KIM, S J ; LEE, G S ; LEE, J S

PATENT-ASSIGNEE: CHEIL IND INC [CHBIN]

PRIORITY-DATA: 2000KR-0083659 (December 28, 2000)

PATENT-FAMILY:

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INT-CL (IPC): G01N021/33

ABSTRACTED-PUB-NO: KR2002054538A

BASIC-ABSTRACT:

NOVELTY - A method for measuring solid density and primary particle size of

slurry is provided to measure solid density and primary particle size

convenient and accurate manner within a short time period, while allowing

slurry quality control to be easily performed.

DETAILED DESCRIPTION - A method for measuring solid density and

particle size comprises the steps of transmitting ultraviolet ray to the slurry

made of deionized water, metal oxide fine powder and additives, measuring

transmissivity, and comparing the measured transmissivity with a calibration

curve. The step of transmitting ultraviolet ray to the slurry uses a cell(5)

of quartz material having an ultraviolet transmission length of 0.1 to 2cm.

The step of measuring transmissivity uses a light source having a wavelength of

300 to 1100nm. The calibration curve is made by using a slurry including a metal oxide having a size same as the size of the slurry.

CHOSEN-DRAWING: Dwg.1/10

TITLE-TERMS: METHOD MEASURE SOLID DENSITY PRIMARY PARTICLE SIZE

SLURRY CHEMICAL
MECHANICAL POLISH PROCESS ULTRAVIOLET SPECTROSCOPE

DERWENT-CLASS: S03

EPI-CODES: S03-E04A5;

